

Notice of References Cited

Application/Control No.

10/674,961

Applicant(s)/Patent Under

Reexamination

CALLEGARI ET AL.

Examiner

Alexander G. Ghyka

Art Unit

2812

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
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FOREIGN PATENT DOCUMENTS

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	N					
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	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Yom et al, Growth of gamma alumina thin films on silicon by MOCVD, Thin Solid Films 1992, pgs 72-75.
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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Alex Ghyka 6/26/08